

## Electronic Patent Application Fee Transmittal

**Application Number:**

**Filing Date:**

**Title of Invention:**

Semiconductor wafer inspection device and method

**First Named Inventor:**

Fumi Nabeshima

**Filer:**

Joseph Patrick Farrar

**Attorney Docket Number:**

PA214WP002

Filed as Large Entity

### U.S. National Stage under 35 USC 371 Filing Fees

**Description**

**Fee Code**

**Quantity**

**Amount**

**Sub-Total in  
USD(\$)**

#### Basic Filing:

National Stage Fee

1631

1

300

300

Natl Stage Search Fee - Report provided

1642

1

400

400

National Stage Exam - all other cases

1633

1

200

200

**Pages:**

**Claims:**

**Miscellaneous-Filing:**

**Petition:**

**Patent-Appeals-and-Interference:**

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Miscellaneous:				
Total in USD (\$)				900